

Femtosecond laser ablation (FESLA) XPS – A novel XPS depth profiling technique for thin films, coatings and multi-layered structures

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The figures below show examples of: (i) FESLA XPS yielding the true composition of InP, which suffers from preferential sputtering of P using ion bombardment: (ii) retention of the correct chemical state information for $\approx 7 \mu\text{m}$ duplex iron oxide layer and ease of profiling to depths beyond that practically achievable using ion beams

